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**On The Cover:** R. E. Sah, L. Kirste, M. Baeumier, P. Hiesinger, V. Cimalla, V. Lebedev, H. Baumann, and H.-E. Zschau, Residual stress stability in fiber textured stoichiometric AlN film grown using RF magnetron sputtering, *JVST, A* **28**(3), Figure 3, 396 (2010).